

Attorney's Docket No.: 06618-662001 Client's Ref. No.: CIT 3252

OFFICIAL COMMUNICATION

FACSIMILE

FOR THE PERSONAL ATTENTION OF:

EXAMINER ALANDRA ELLINGTON

GROUP 2855 FAX NO: 703-872-9319

45 Number of pages including this page

Applicant: Yu-Chong Tai et al.

Serial No.: 09/900,743

: July 6, 2001

Art Unit : 2855

Examiner: Alandra Ellington

Confirmation No.: 4560

FACSIMILE COMMUNICATION

Title

Filed

: Surface-micromachined pressure sensor and high pressure application

Commissioner for Patents Washington, D.C. 20231

Sir:

Attached to this facsimile communication cover sheet is a Response to Final Office Action, faxed this 22nd day of August, 2002, to Group 2855, the United States Patent and Trademark Office.

Date: August 22, 2002

ott C. Harris /rpi Reg. No. 32,030

Respectfully submitted,

Fish & Richardson P.C. Customer Number: 20985

4350 La Jolla Village Drive, Suite 500

San Diego, California 92122 Telephone: (858) 678-5070

Fax: (858) 678-5099

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Art Unit: 2855

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Title

: SURFACE-MICROMACHINED PRESSURE SENSOR AND HIGH

PRESSURE APPLICATION

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Commissioner for Patents Washington, D.C. 20231

IAUG 2 2 2002

RESPONSE

TECHNOLOGY CENTER 2800

In response to the official action mailed 05/22/02, paper no. 2 in the above referenced case, please amend the application as follows:

In the specification:

Please replace the paragraph beginning at page 4, paragraph number [0023] with the following rewritten paragraph:

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08/27/2002 TYUMS

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Figure 1 shows a cross-section of the surface micromachined piezoresistive high-pressure sensor according to an embodiment. Strain sensitive resistors 102, such as polysilicon piezoresistors, may be placed in a location where they are sensitive to the strain caused by diaphragm movement. Other materials, such as platinum, can also be used. In a cross-section, strain sensitive resistors 102, 104 are shown within a

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I hereby certify that this correspondence is being transmitted by facsimile to the Patent and Trademark Office on the date indicated below.

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